IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Daniel Stearns et al.

Attorney Docket: CIL-10843

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Examiner: R. Kunemund

For

: A Method To Repair Localized Amplitude Defects In A EUV Lithography Mask Blank

APPLICATION FOR **CHANGE IN CORRESPONDENCE ADDRESS**

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

Please change the Correspondence Address for the above-identified

application to:

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If you have any questions, please contact the undersigned at 808-875-0012.

Respectfully submitted,

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Dated: September 27, 2004

Registration No. 38,725